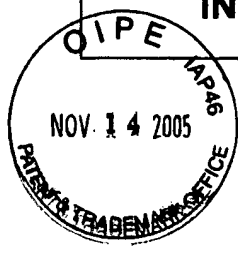


Ifw



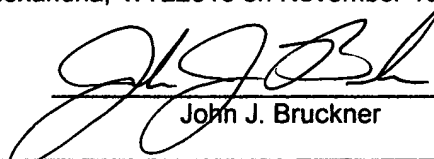
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE	
INFORMATION DISCLOSURE STATEMENT	
Atty. Docket No. UBAT1530	
Applicant(s) Michael A. Guillorn	
Application Number 10/716,770	Date Filed November 19, 2003
For VERTICALLY ALIGNED NANOSTRUCTURE SCANNING PROBE MICROSCOPE TIPS	
Group Art Unit 2881	Examiner Fernandez, Kalimah
Confirmation Number: 6209	

Mail Stop Amendment
Commissioner for Patents
PO Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Certificate of Mailing Under 37 C.F.R. 1.8

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313 on November 10, 2005.

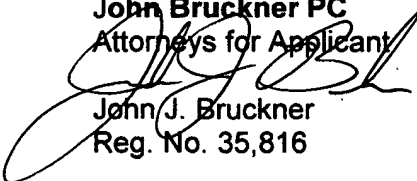

John J. Bruckner

Applicant respectfully requests, pursuant to 37 C.F.R. §§ 1.56, 1.97 and 1.98, that the reference(s) listed on the attached PTO/SB/08A and/or PTO/SB/08B forms be considered and cited in the examination of the above-identified application. Pursuant to 37 C.F.R. §§ 1.97(g) and (h), no representation is made that a search has been made or that this art is material to the patentability of the present application.

Copies of the [non-US patent] reference(s) is(are) enclosed for the convenience of the Examiner. This Information Disclosure Statement is being filed after mailing of a First Office Action. Applicant hereby requests consideration of this Information Disclosure Statement pursuant to 37 C.F.R. § 1.97(c)(2).

A check in the amount of \$180 representing the fee set forth in 37 CFR § 1.17(p) is enclosed. While Applicants believe no (further) fees are due, if any (further) fees are due, the Commissioner is hereby authorized to charge any fees or credit any overpayments to Deposit Account No. 50-3204 of John Bruckner PC.

Dated: November 10, 2005
5708 Back Bay Lane
Austin, TX 78739
Tel. (512) 394-0118
Fax. (512) 394-0119

Respectfully submitted,
John Bruckner PC
Attorneys for Applicant

John J. Bruckner
Reg. No. 35,816

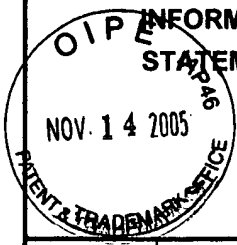
Application Number	10/716,770
Filing Date	November 19, 2003
First Named Inventor	Guillorn
Group Art Unit	2881
Examiner Name	Fernandez, Kalimah
Attorney Docket	UBAT1530

Sheet	1	of	1
-------	---	----	---

[illegible]

Examiner Initials	Cite No.	FOREIGN PATENT DOCUMENTS			Publication Date MM-DD-YYYY (Number 43)	Name of Patentee or Applicant of Cited Document
		Country Code	Number	Kind Code (if known)		

Date
Considered

		INFORMATION DISCLOSURE STATEMENT BY APPLICANT		Application Number	10/716,770
		Filing Date	November 19, 2003		
		First Named Inventor	Guillorn		
		Group Art Unit	2881		
		Examiner Name	Fernandez, Kalimah		
Sheet 1	of 2	Attorney Docket Number		UBAT1530	

NON-PATENT LITERATURE DOCUMENTS

Examiner Initials	Cite No.	Citation
		"Scanning tunneling microscopy on rough surfaces: tip-shape-limited resolution" G. Reiss, J. Vancea, H. Wittmann, J. Zweck, and H. Hoffmann, J. Appl. Phys. 67 , 1156 (1990)
		"Scanning probe metrology" J. E. Griffith, D. A. Grigg, M. J. Vasile, P. E. Russell, and E. A. Fitzgerald J. Vac. Sci. Technol. A 10 , 674 (1992)
		"Characterization of scanning probe microscope tips for linewidth measurement" J. E. Griffith, D. A. Grigg, M. J. Vasile, P. E. Russell, and E. A. Fitzgerald, J. Vac. Sci. Technol. B 9 , 3586 (1991)
		"Scanning probe tip geometry optimized for metrology by focused ion beam ion milling" M. J. Vasile, D. Grigg, J. E. Griffith, E. Fitzgerald, and P. E. Russell J. Vac. Sci. Technol. B, 9 , 3569 (1991)
		"Scanning probe tips formed by focused ion beams" M. J. Vasile, D. A. Grigg, J. E. Griffith, E. A. Fitzgerald, and P. E. Russell, Rev. Sci. Instrum., 62 , 2167 (1991)
		"Formation of probe microscope tips in silicon by focused ion beams" M.J. Vasile, C. Biddick and H. Huggins. Appl. Phys. Lett., 64 , 575 (1994)
		"Sharpened electron beam deposited tips for high resolution atomic force microscope lithography and imaging" M. Wendel, H. Lorenz and J.P. Kotthaus, Appl/ Phys. Lett. 67 , 3732 (1995)
		"Mechanical properties of high-aspect-ratio atomic force microscope tips" G. Janchen, P. Hoffmann, A. Kriele, H. Lorenz, A.J. Kulik, and G. Dietler, Appl. Phys. Lett., 80 , 4623 (2002)
		"Carbon-nanotube tips for scanning probe microscopy: Preparation by a controlled process and observation of deoxyribonucleic acid" H. Nishijima, S. Kamo, S. Akita, Y. Nakayama, K.I. Hohmura, S.H. Yoshimura and K. Takeyasu, Appl. Phys. Lett. 74 , 4061 (1999)
		"WS ₂ nanotubes as tips in scanning probe microscopy" A. Rothschild, S.R. Cohen, R. Tenne, Appl. Phys. Lett. 75 , 4025 (1999)
		"Growth and fabrication with single-walled carbon nanotube probe microscopy tips" C.L. Cheung, J.H. Hafner, T.W. Odom, K. Kim and C.M. Lieber, Appl. Phys. Lett, 76 , 3136 (2000)
Examiner Signature		Date Considered

INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Application Number	10/716,770
				Filing Date	November 19, 2003
				First Named Inventor	Guillorn
				Group Art Unit	2881
				Examiner Name	Fernandez, Kalimah
Sheet	2	of	2	Attorney Docket Number	UBAT1530

NON-PATENT LITERATURE DOCUMENTS

Examiner Initials	Cite No.	Citation
		"Improved fabrication approach for carbon nanotube probe devices" R. Stevens, C. Nguyen, A. Cassel, L. Delzeit, M. Meyyappan and J. Han, Appl. Phys. Lett, 77 , 3453 (2000)
		"Carbon nanotube tip probes: stability and lateral resolution in scanning probe microscopy and application to surface science in semiconductors" C.V. Nguyen, K.J. Chao, R.M.D. Stevens, L. Delzeit and M. Meyyappan. Nanotechnology, 12 , 363 (2001)
		"Wafer scale production of carbon nanotube scanning probe tips for atomic force microscopy" E. Yenilmez, Q. Wang, R.J. Chen, D. Wang, and H. Dai, 80 , 2225 (2002)
		"Single-wall carbon nanotube atomic force microscope probes" E.S. Snow, P.M. Campbell and J.P. Novak, Appl. Phys. Lett. 80 , 2002 (2002)
		"Catalytic growth of carbon filaments" R. T. K. Baker, Carbon, 27 , 315 (1989)
		"Patterned growth of individual and multiple vertically aligned carbon nanofibers" V. I. Merkulov, D. H. Lowndes, Y. Y. Wei, G. Eres, and E. Voelkl, Appl. Phys. Lett., 76 , 3555 (2000)
		"Shaping carbon nanostructures by controlling the synthesis process" V. I. Merkulov, M. A. Guillorn, D. H. Lowndes, M. L. Simpson, and E. Voelkl, Appl. Phys. Lett., 79 , 1178 (2001)
		"Sharpening of carbon nanocone tips during the synthesis process" V. I. Merkulov, A. V. Melechko, M. A. Guillorn, D. H. Lowndes, and M. L. Simpson, Chem. Phys. Lett., 350 , 381 (2001)
		"Controlled alignment of carbon nanofibers in a large-scale synthesis process" V. I. Merkulov, A. V. Melechko, M. A. Guillorn, D. H. Lowndes, and M. L. Simpson, Appl. Phys. Lett. 80 , 4816 (2002)
		"Microfabricated field emission devices using carbon nanofibers as cathode elements" M.A. Guillorn, A.V. Melechko, L.R. Baylor, V. I. Merkulov, E.D. Ellis, G.J. Bordonaro, M. L. Simpson and D.H. Lowndes, J. Vac. Sci. Technol. B 19 , 2598 (2001)
		"Self-aligned gated field emission devices using single carbon nanofiber cathodes" M. A. Guillorn, A. V. Melechko, V. I. Merkulov, D. K. Hensley, M. L. Simpson, and D. H. Lowndes, Appl. Phys. Lett. 81 , 3660 (2002)
		"Individually addressable vertically aligned carbon nanofiber-based electrochemical probes" M.A. Guillorn, A.V. Melechko, T.E. McKnight, D.W. Austin, V.I. Merkulov, M.L. Simpson and D.H. Lowndes, J. Appl. Phys. 91 , 3824 (2002)
Examiner Signature		Date Considered